

Amendments to the Specification

Please replace the paragraph at page 2, lines 20 through 27 with the following amended paragraph:

Equipment used in the semiconductor industry can also act as a source of contaminants. Stainless steel components ~~can leach~~ can leach metals including iron, chromium and nickel as metal complexes or metal ions. Leached metals are volatile at low concentrations, ppb to parts per trillion (ppt), and are readily captured in the gas phase resulting in potential contamination of silicon wafers or other high purity products. Therefore, all equipment for use in the semiconductor manufacturing process must be thoroughly cleaned to remove potential surface contaminants.